XPS study of RuO₂ films deposited by reactive sputtering

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The conductive metallic oxide, RuO2, has been recently the subject of numerous studies as a bottom electrode for ferroelectric thin film capacitors because of its excellent electrical and diffusion barrier characteristics. The sputter-deposited RuO2 film may be amorphous or polycrystalline according to the deposition conditions. Electrical properties vary as the phase of RuO2 film. The resistivity of the polycrystalline film is lower than that of the amorphous film. In transition metal compounds, the valence d-electrons play an important role in the electrical properties. In case of RuO2 single crystal, the resistivity is associated mainly with electron-phonon scattering.

In the present work, the relationship between the electrical properties and the electronic structures of the RuO2 films has been investigated using a monochromatic X-ray photoelectron spectroscopy (XPS). Core level spectra of XPS did not show any distinctive difference between the observed phases. The valence band spectra, however revealed a characteristic relationship between them. A sharp valence d-band near the Fermi edge, which is closely related to the film conductivity, has been observed in the polycrystalline film while a broad valence d-band has been observed in the amorphous film. The valence band structure and its contribution to the electrical properties of RuO2 films will be further discussed.